

Information Disclosure Citation in an Application	Application No.	Applicant(s)	
	Unassigned	Pascal Huyghe et al.	
	Docket Number 064441.0263	Group Art Unit Unknown	Filing Date June 27, 2003

U.S. PATENT DOCUMENTS

		DOCUMENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE
A.							
B.							
C.							
D.							
E.							
F.							
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H.							
I.							
J.							
K.							

FOREIGN PATENT DOCUMENTS

		DOCUMENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
							YES	NO
L.								
M.								
N.								
O.								
P.								
Q.								

NON-PATENT DOCUMENTS

		DOCUMENT (Including Author, Title, Source, and Pertinent Pages)	DATE
MA	R.	Edward Sutile et al.'s "Streamlining the front-end reticle fabrication process by improving mask ordering" at internet address < http://www.micromagazine.com/archive/02/06/sutile.html > and published in June 2002 Issue of Micro Magazine. 10 Pages	June 2002
MA	S.	Brock Hotaling, "MaskPilot Revolutionizes Semiconductor Software," <u>Reticle and Mask Solutions</u> , Vol. I, No. 1, Fall 2002, 4 Pages	Fall 2002
	T.	Photronics, Inc., "Photronics eBeam Phase Masks: Tackling the Challenges of Special Lightwave Applications." <u>Reticle and Mask Solutions</u> , Vol. XIII, No. 1, Spring 2002, 4 Pages	Spring 2002

EXAMINER	DATE CONSIDERED
<i>Haynaf</i>	21/24/2006

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the applicant.